

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination GENETTI ET AL.	
		Examiner McDieunel Marc	Art Unit 3661	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,648,730 B1	11-2003	Chokshi et al.	451/6
	B	US-6,327,517	12-2001	Sundar, Satish	700/245
	C	US-6,629,053 B1	09-2003	Mooring, Benjamin W.	702/94
	D	US-6,063,196 A	05-2000	Li et al.	118/712
	E	US-6,591,160 B2	07-2003	Hine et al.	700/218
	F	US-6,188,323 B1	02-2001	Rosenquist et al.	340/686.5
	G	US-5,382,806 A	01-1995	Bacchi et al.	250/559.29
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Lento, Wafer Handling And FAB Automation: Using an integrated controller to manage wafer-handling systems, 2001, Internet, pp. 1-8
	V	Berkeley Process Control, Inc., Semiconductor Components, 2003, Internet, pp. 1-2
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.